Xactix Xenon Difluoride Etcher

Manager: Vince Genova
Backup: Meredith Metzler

Work Phone
Manager: 254-4907
Backup: 254-4934

Calls to staff phones will be automatically forwarded to their cell phones during accessible hours. At other times leave a message or send them an email.

Safety
- System uses a vapor Fluorine source for etching - use caution during operation
- No buddy system restrictions

Process Restrictions
Material Restrictions
- Wafers up to 6" including pieces are allowed

Parameter Restrictions
- Do not etch more than 2 microns of a blanket Si film
- No flow through processing. Normal and Advanced normal modes only.

Scheduling / Sign-up Restrictions
- None

Requirements (Do Every Time)
- Log tool when finished
- Turn off touch-screen monitor when done.

Prohibitions (Never Do)
- None

Common Problems
Problem: ___________________________  Root Cause: ___________________________  Solution: ___________________________

Other Comments or Cautions